

BASIS™ Mass Flow Controller

MEMS BASED FLOW CONTROL FOR OEM APPLICATIONS

*100 ms control
response*

*Tiny device
footprint*

*Flow ranges from
1 SCCM to 50 SLPM*

*Ready-to-ship
inventory*

*Instant
warm-up*



Shown actual size

Small. Easy. Fast.

MEMS BASED FLOW CONTROL FOR OEM APPLICATIONS



Quick Specifications:

Full Scale Ranges:

- 1–100 SCCM
- 5–1000 SCCM
- 0.1–20 SLPM
- 0.25–50 SLPM

Accuracy:

- ±1.5% of the reading and
- ±0.5% full-scale (NIST-traceable)

Repeatability:

- 0.5% of reading

Custom calibrations:

- Device can be calibrated for use with:
Air, Ar, CO₂, N₂, O₂, N₂O, He, or H₂

Signals:

- RS-232/485 digital and 0–5 Vdc
analog, customizable to any range
within 0–5 Vdc

Communications:

- MODBUS-RTU and ASCII serial

Process connections:

- NPT or SAE forms

Fast in Every Way

- **100 ms control response**
Stills upstream fluctuations
- **Instant warm-up**
Measures at full accuracy in 70 ms
- **Accessible control valve tuning**
for best speed and stability
- **Ready to ship**
Versatile stock reduces lead time

Selected Applications

Flow Control for OEM Gas Analyzers

Feed stable gas flows to the sensors within OEM analyzer products. Small size, instant control readiness

and dual communications make BASIS easy to build into end user products.



Automated Gas Mixing

Populate your gas mixing cabinets with responsive BASIS mass flow controllers. They're ready in an instant for flow measurement at full accuracy.

Fast analog and digital feedback to a PLC or PC allows real-time changes to the flow rate setpoint to maintain desired gas mixture composition.

